

ABSTRACT

[00262] A substrate inspection device includes a substrate rotating device for holding a substrate on a holding surface and causing rotation, a disk having a disk body rotatably supported on a base and three lift cams fixed to an upper side of the disk body and formed with cam faces that are inclined surfaces inclined in the rotational direction, and a lifter having a lifter body with a support surface on which the substrate is mounted and guiding in the vertical direction and lifter driven sections respectively projecting to and fixed to a lower side of the lifter body, where lower sides of the lifter driven sections respectively contact the cam faces in a sliding manner at contact points, and if the contact points are moved to an upper side of the inclined surfaces the support surface becomes higher than the holding surface.

[00263] With this structure, it is possible to provide a substrate inspection device and substrate inspection method that can improve measurement precision, and a substrate inspection device, substrate inspection method and recovery tool suitable for causing a droplet to adhere to an outer surface of a substrate and move along the outer surface.

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